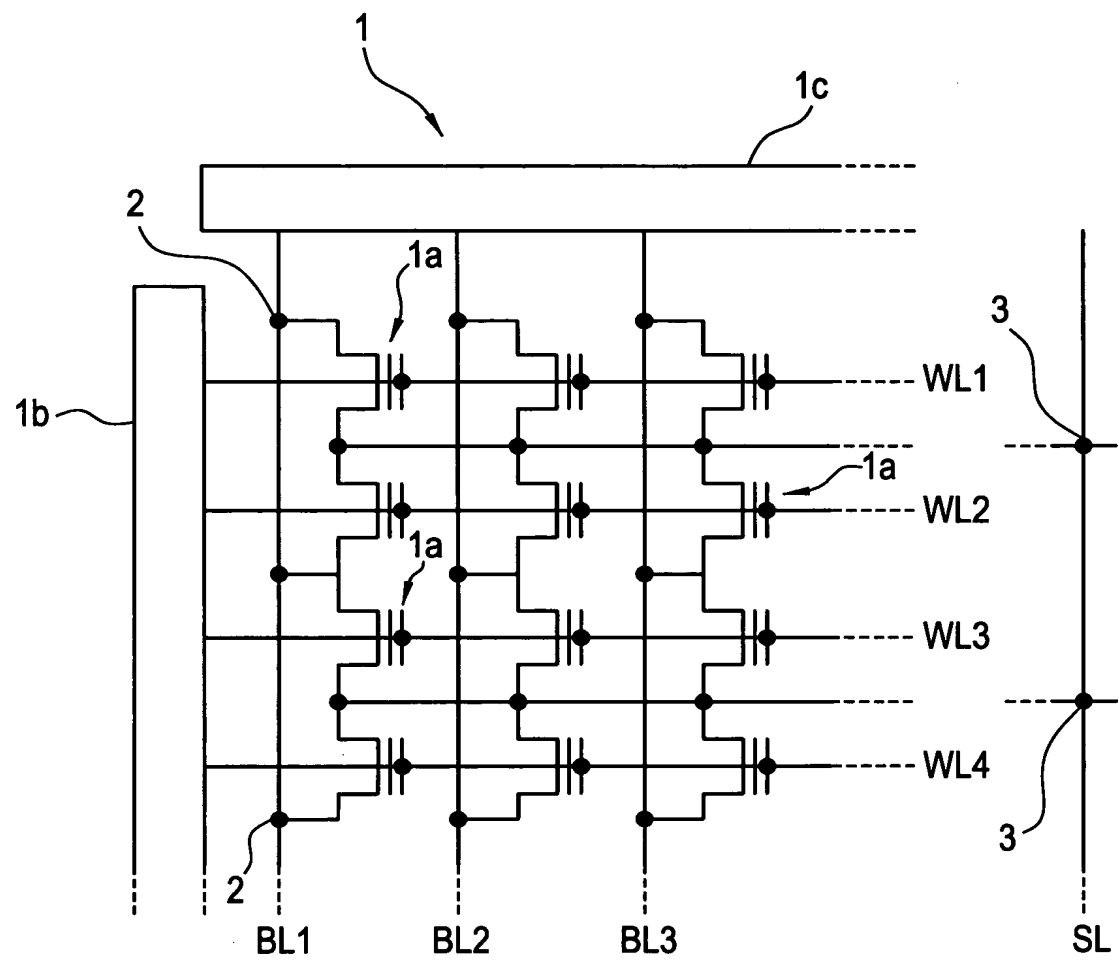


APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		



FIG. 1

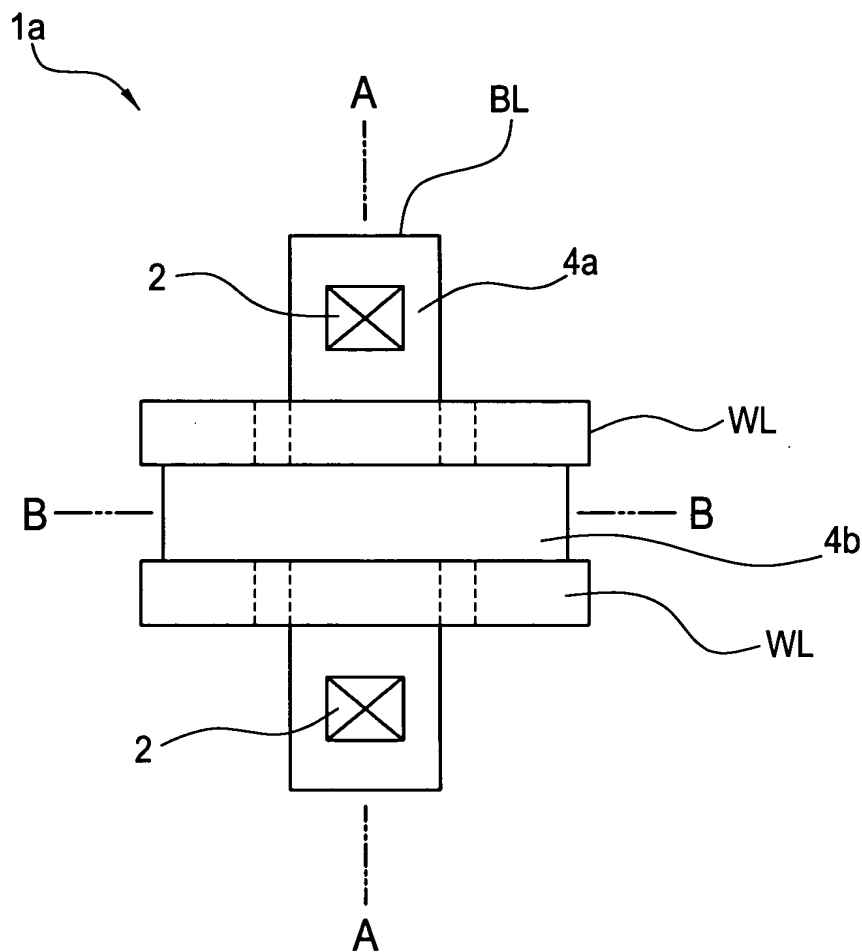


APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

2/20

FIG. 2



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

3/20

FIG. 3A

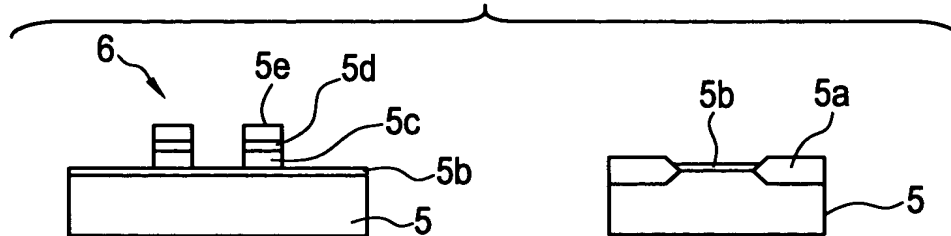


FIG. 3B

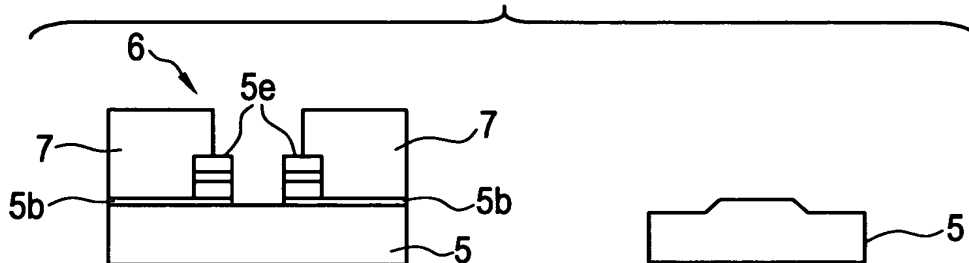


FIG. 3C

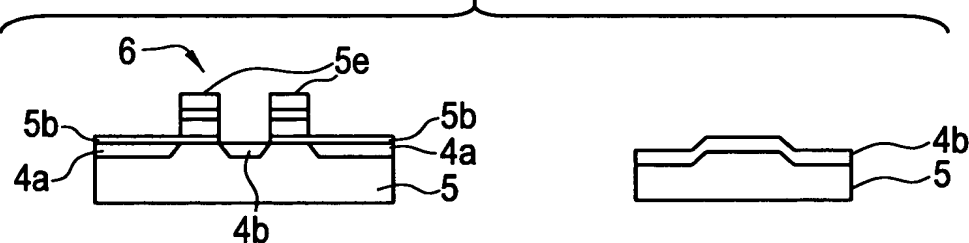


FIG. 3D

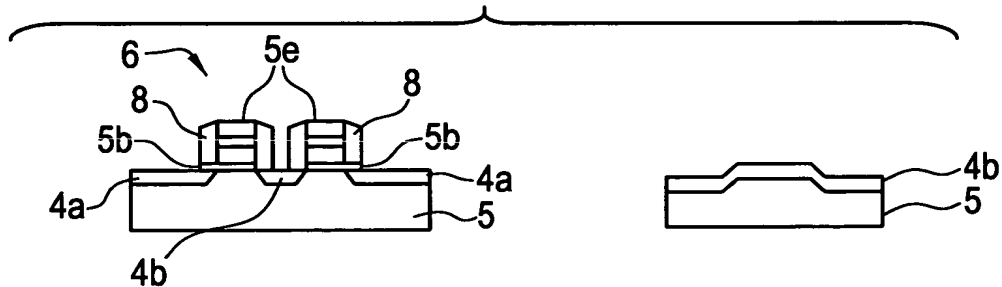
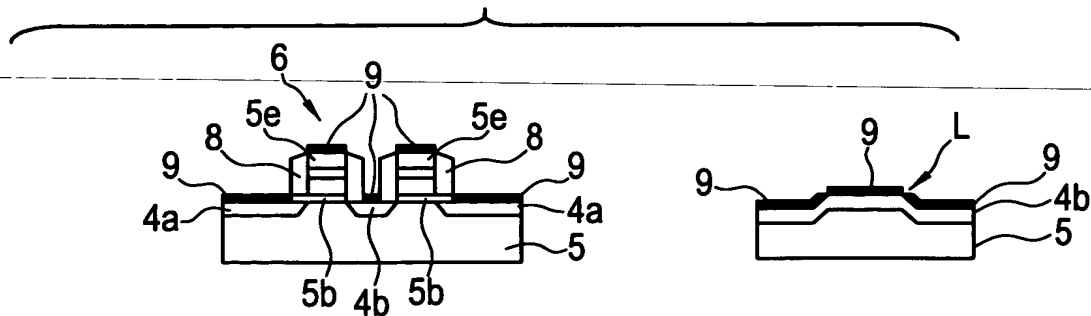


FIG. 3E

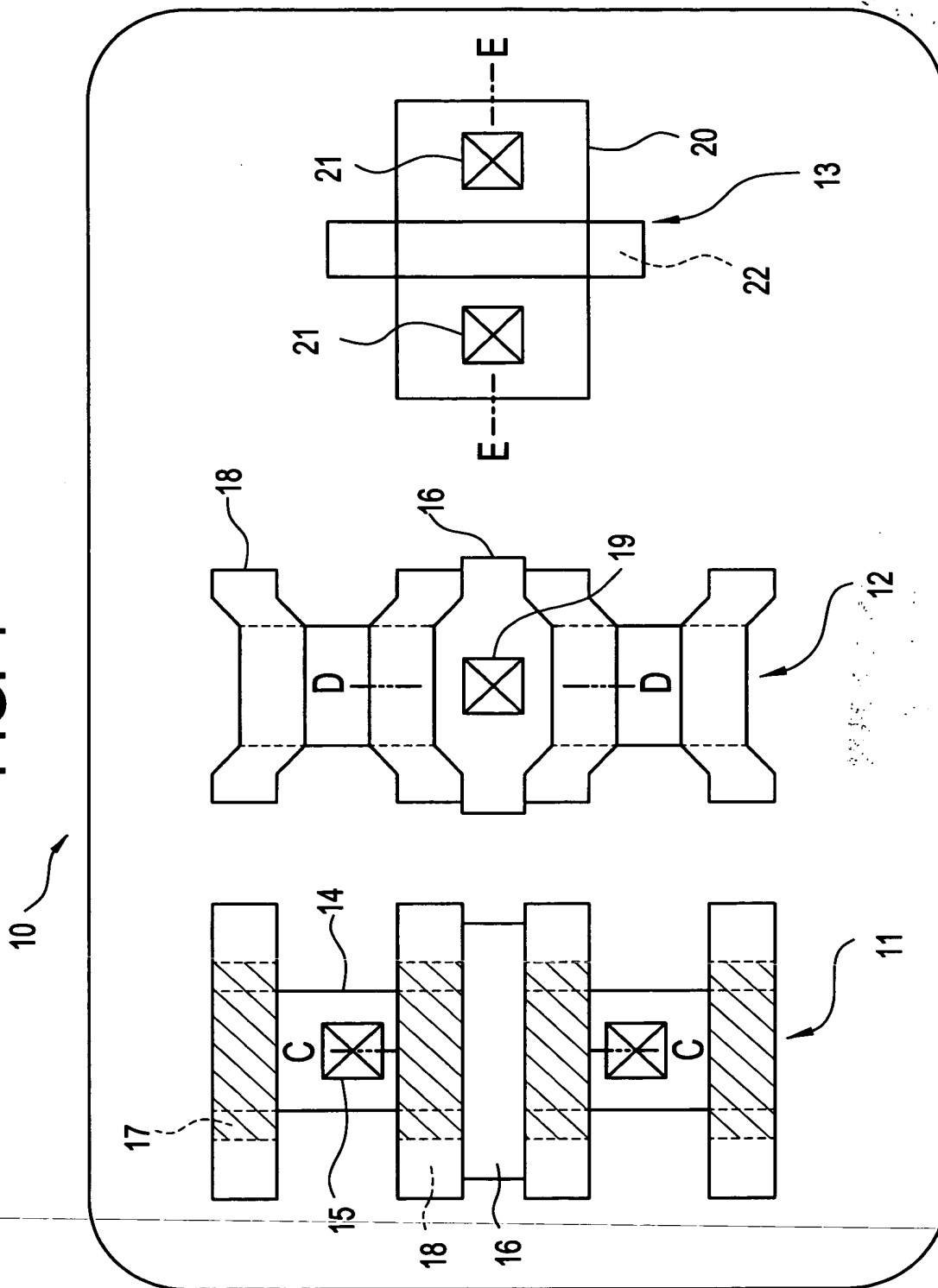


APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

4/20

FIG. 4

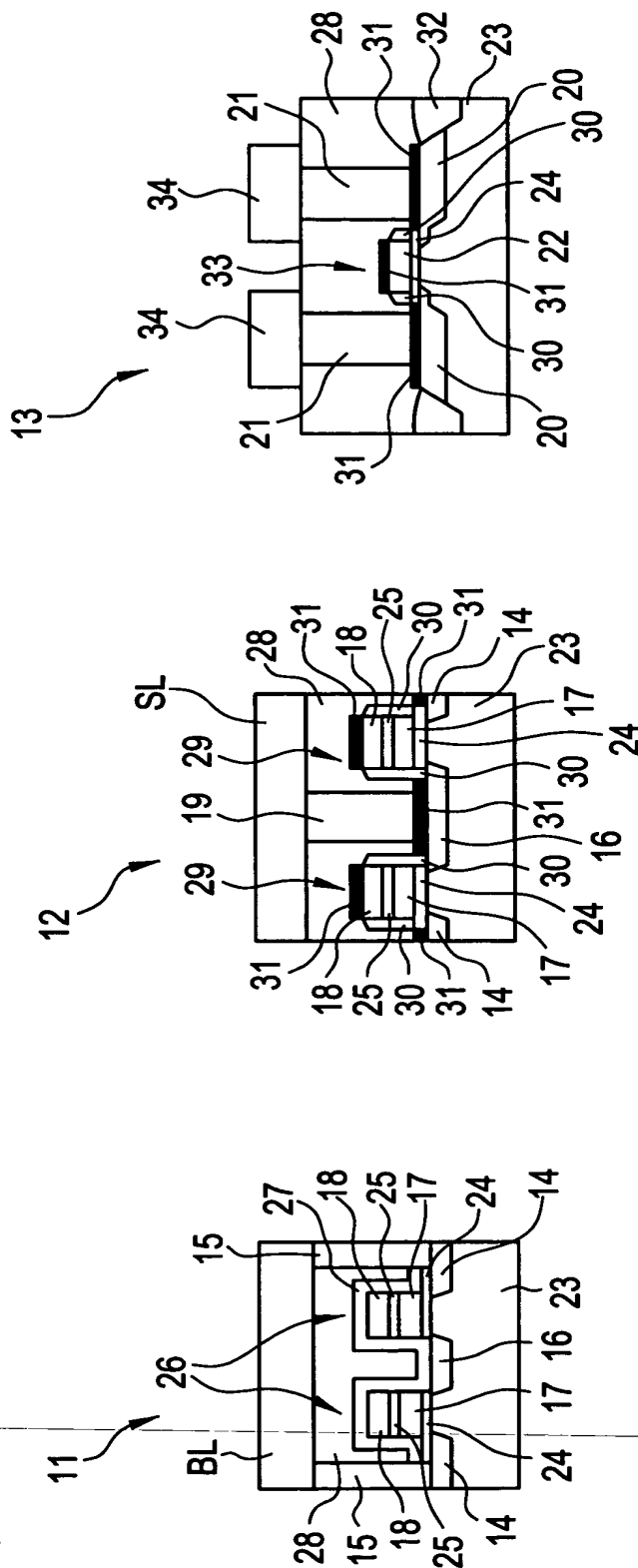


APPROVED	O.G. FIG.
BY	CLASS SUBCLASS
DRAFTSMAN	

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

5/20

FIG. 5



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

6/20

FIG. 6A

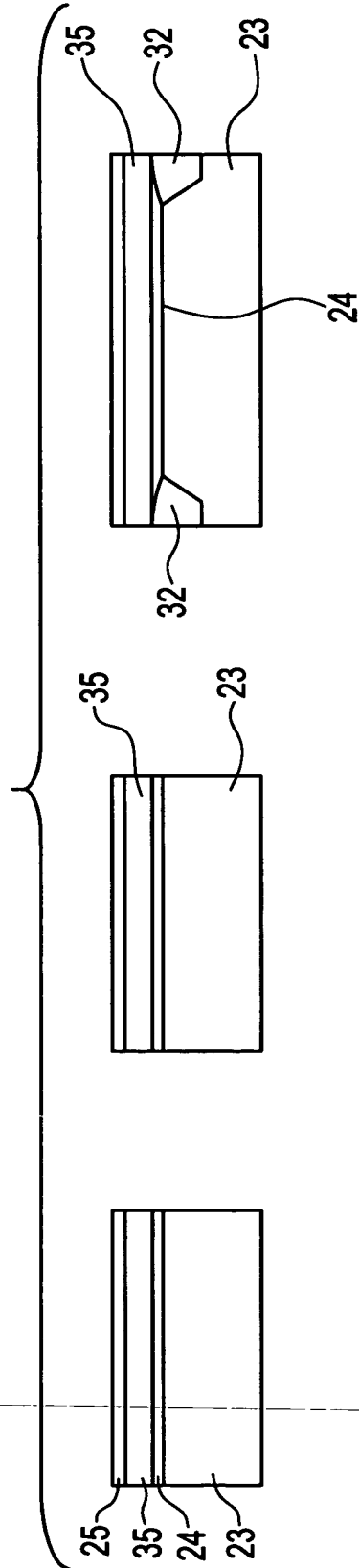
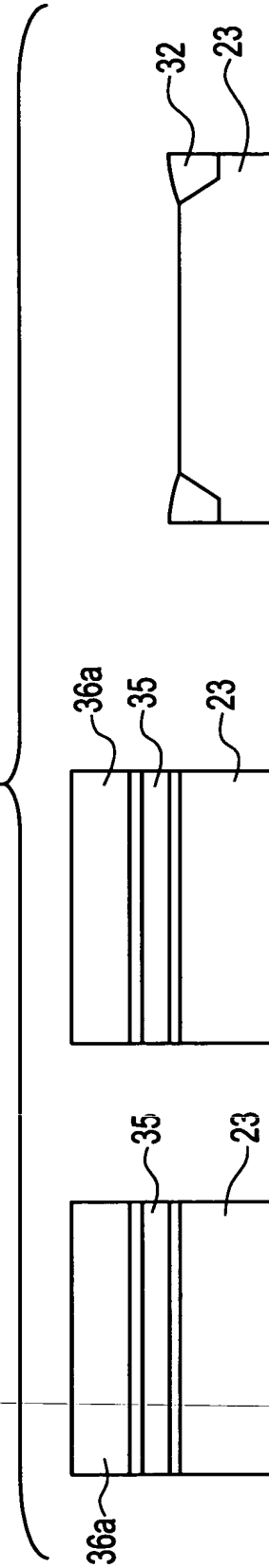


FIG. 6B



APPROVED	O.G. FIG.
BY	CLASS. SUBCLASS
DRAFTSMAN	

Fumihiko HAYASHI
 emiconductor Storage Apparatus and
 Manufacturing Method Thereof
 Q62964---Filed May 25, 2001

7/20

FIG. 6C

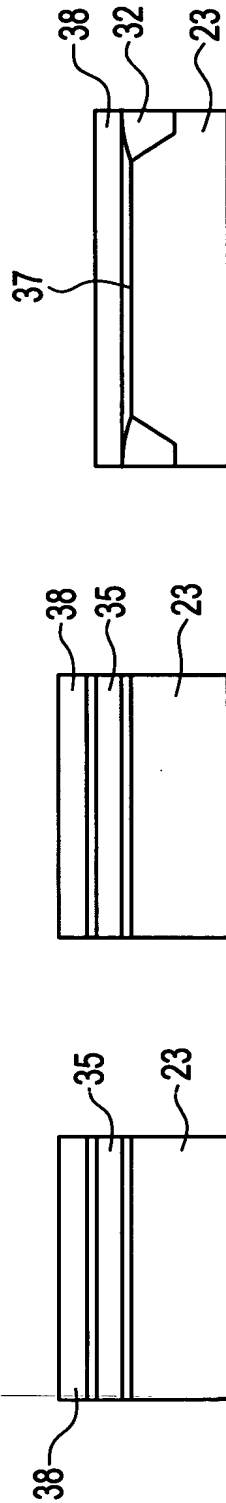
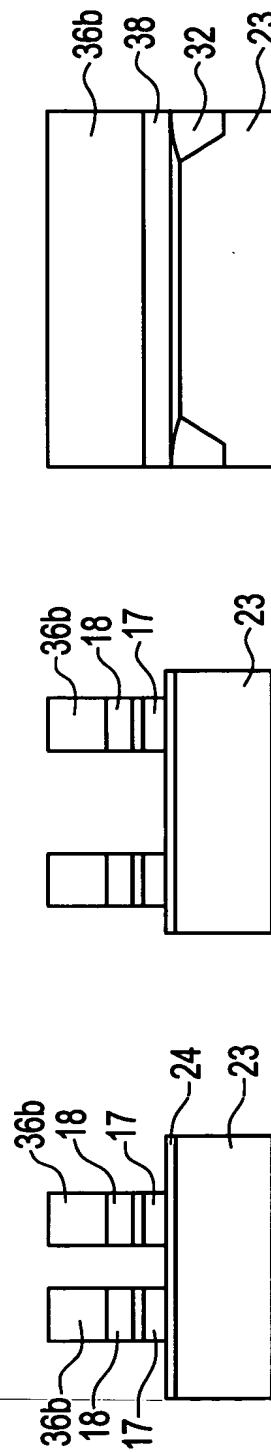


FIG. 6D



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

8/20

FIG. 6E

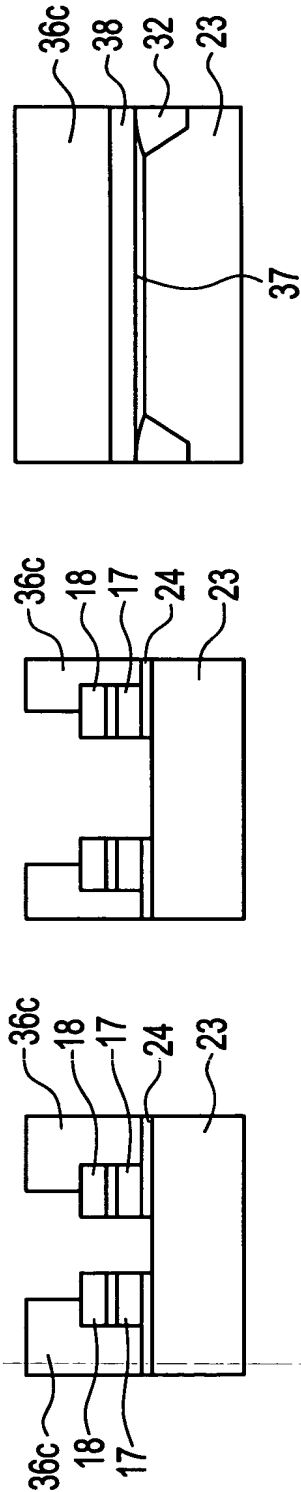
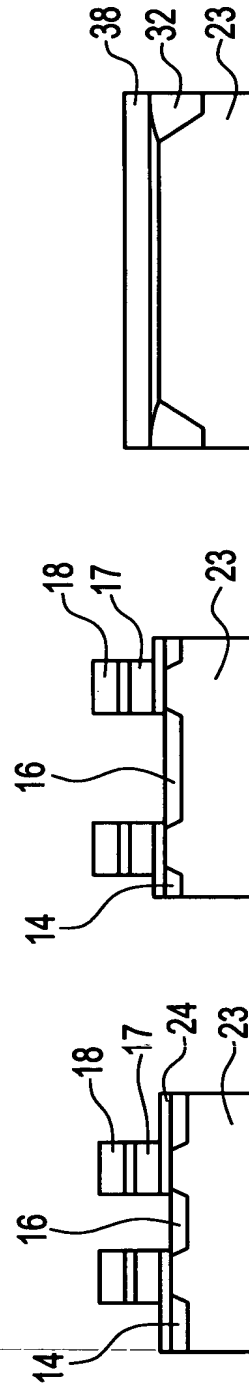


FIG. 6F



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

9/20

FIG. 6G

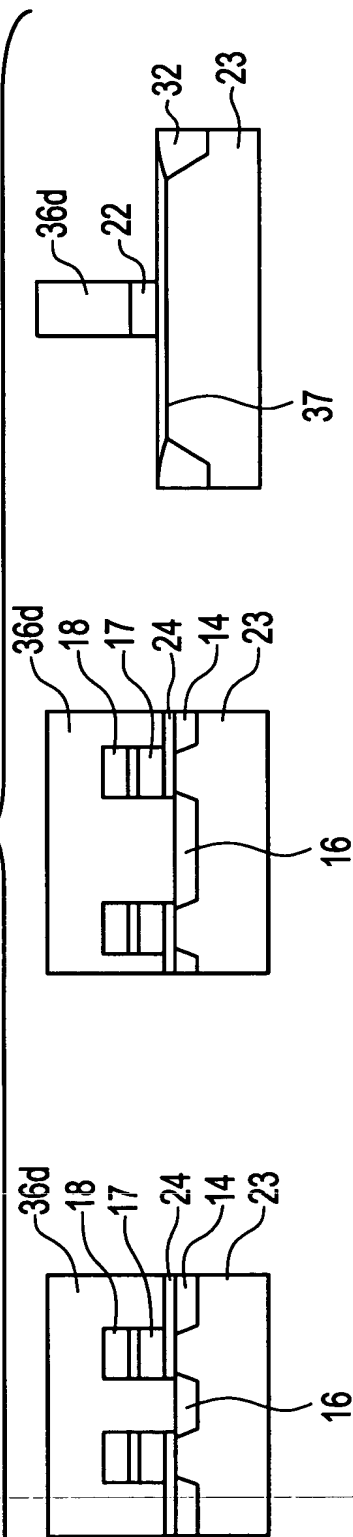
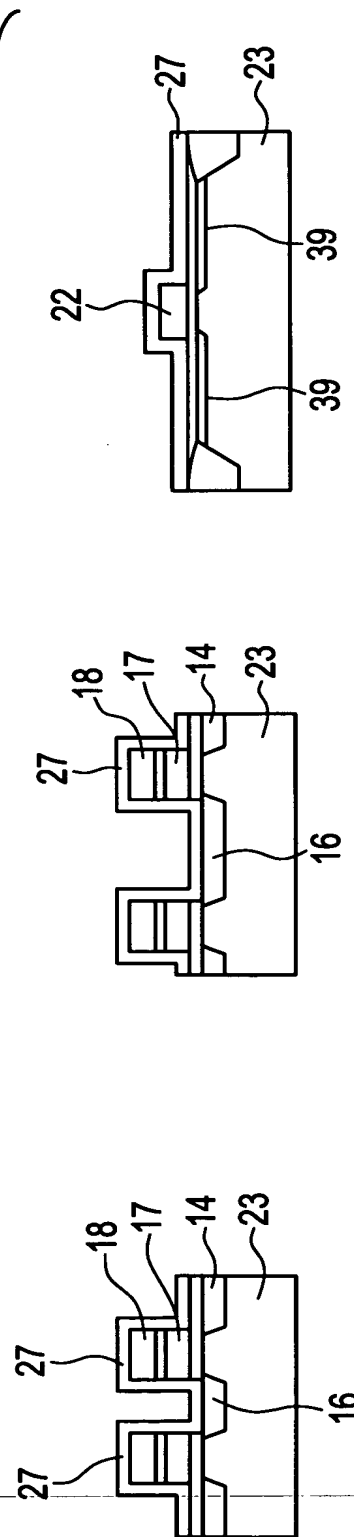


FIG. 6H



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

10/20

FIG. 6I

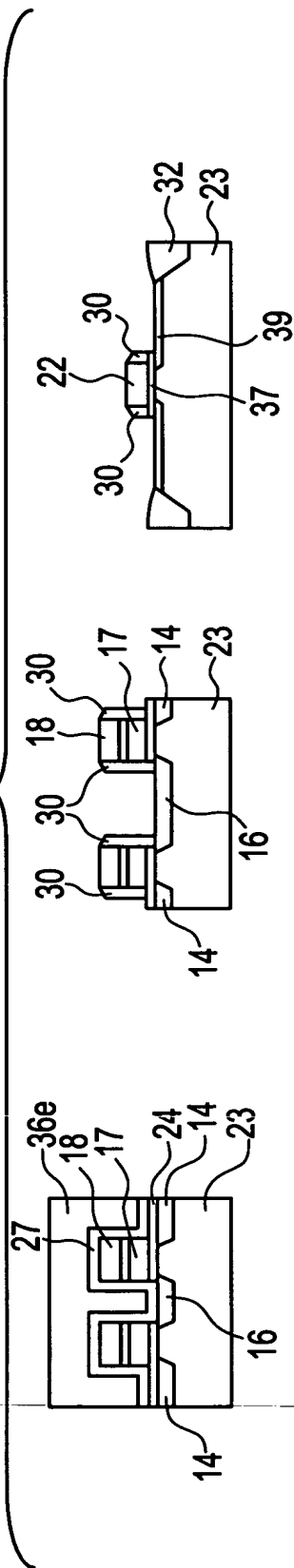


FIG. 6J

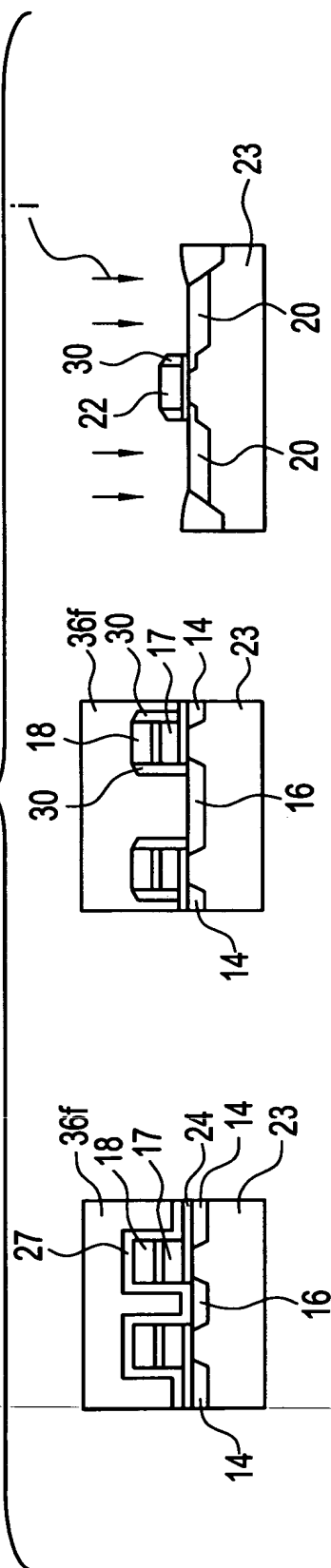
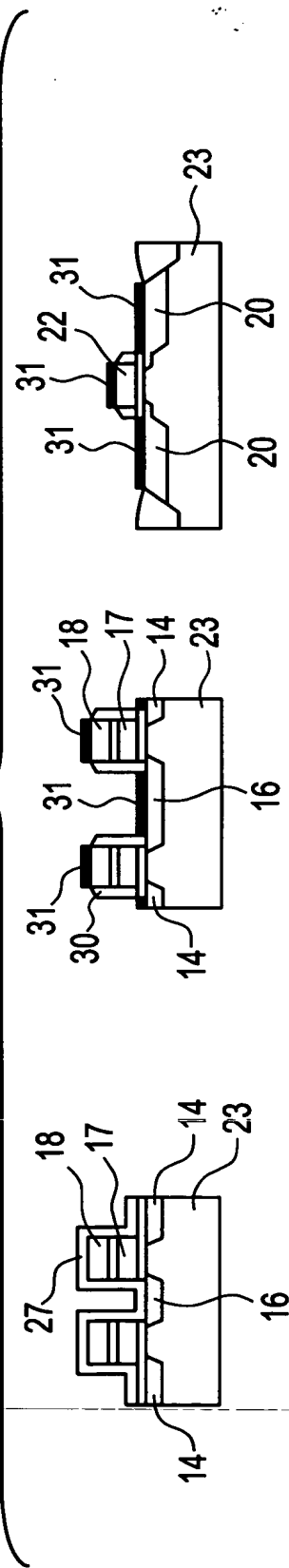


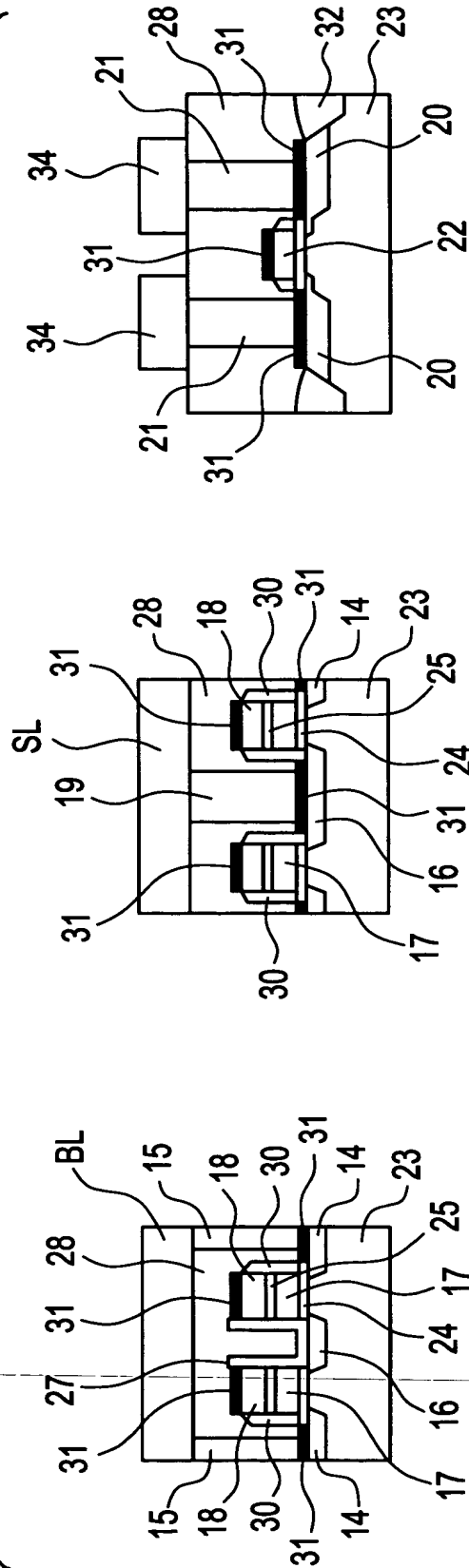
FIG. 6K



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

11/20

FIG. 7



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

12/20

FIG. 8A

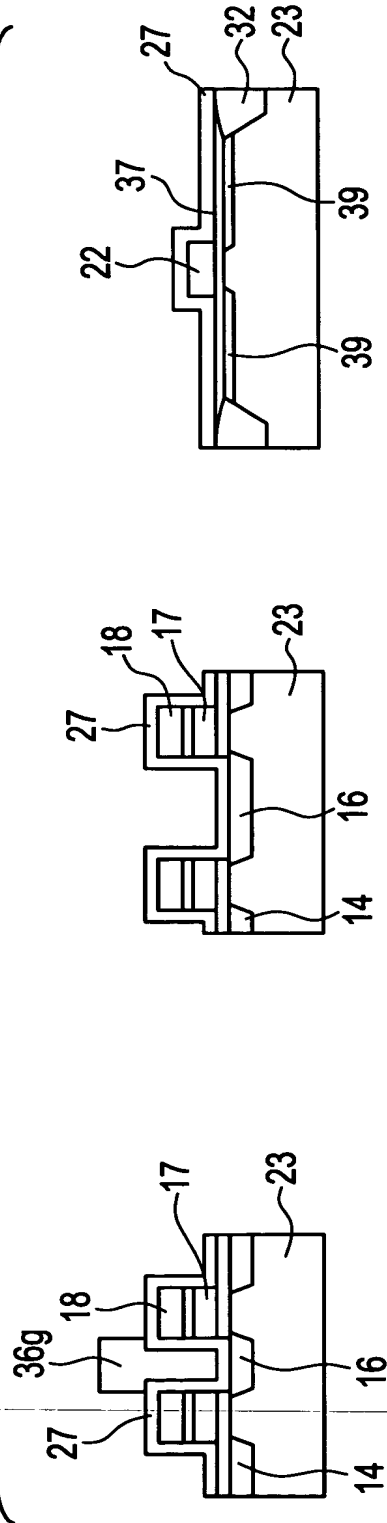
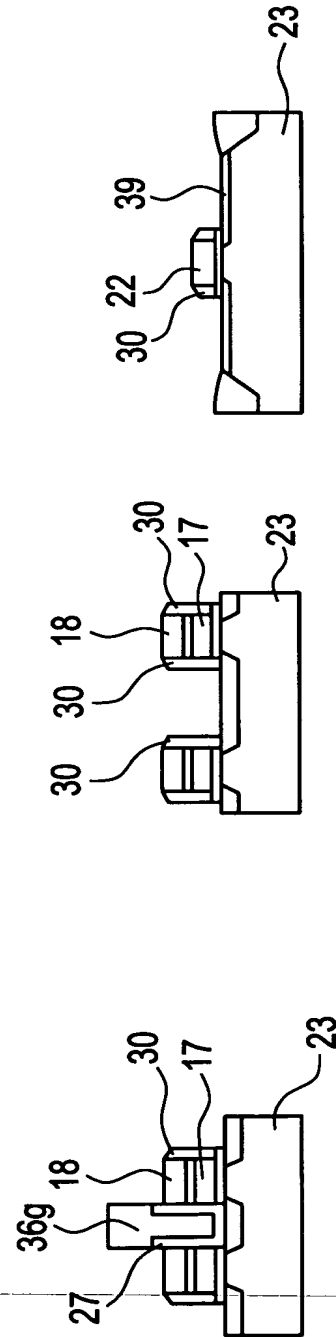


FIG. 8B



APPROVED	O.G. FIG.
BY	CLASS, SUBCLASS
DRAFTSMAN	

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

13/20

FIG. 8C

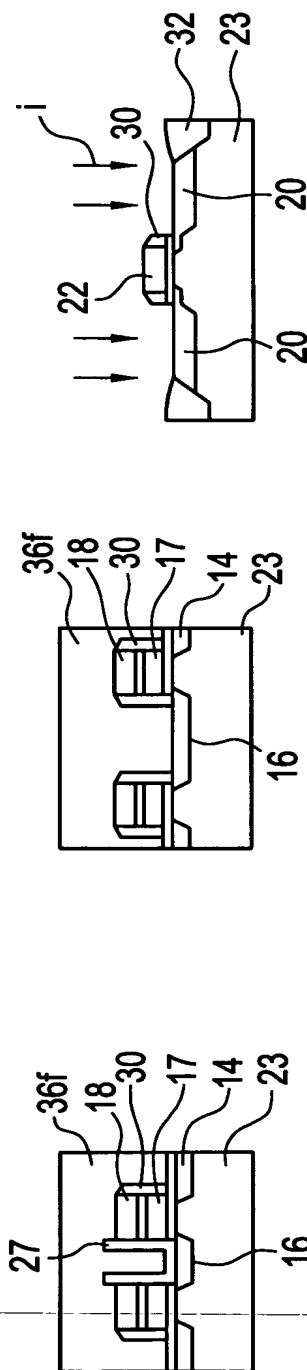


FIG. 8D

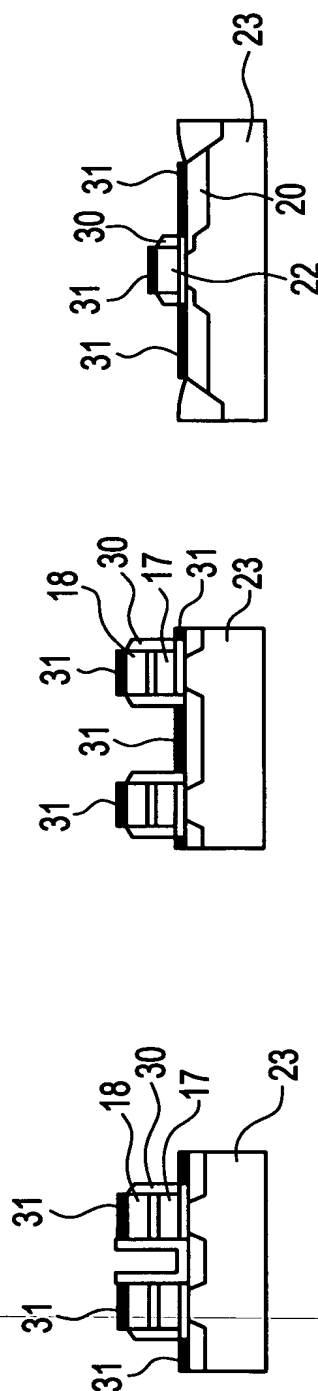
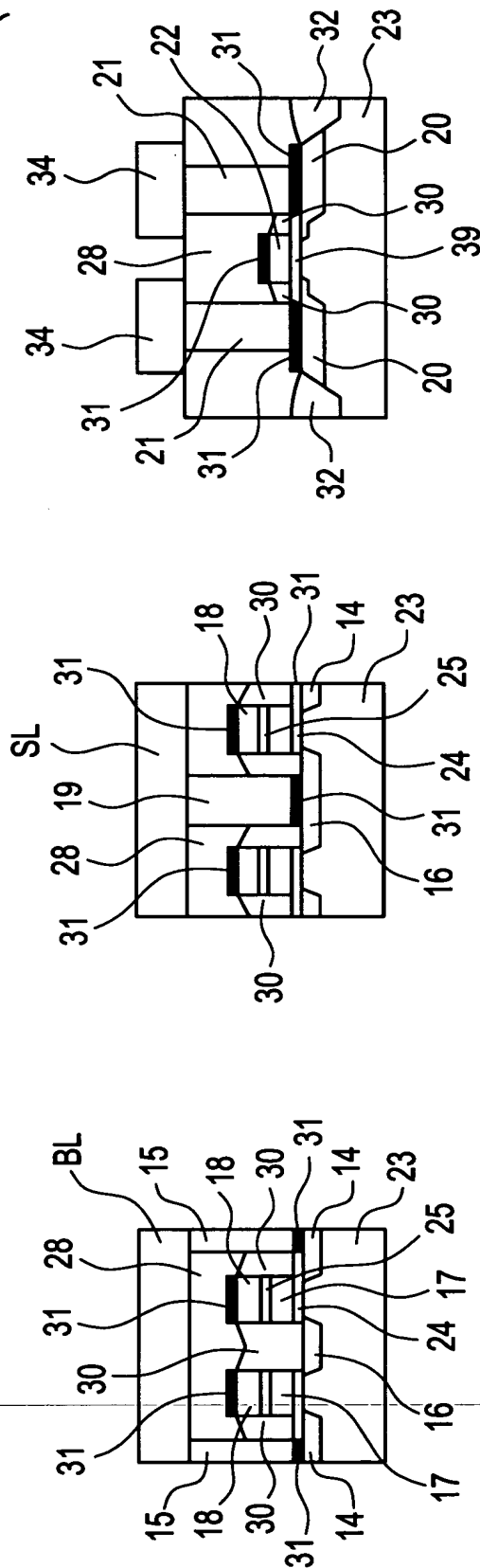


FIG. 9



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

15/20

FIG. 10A

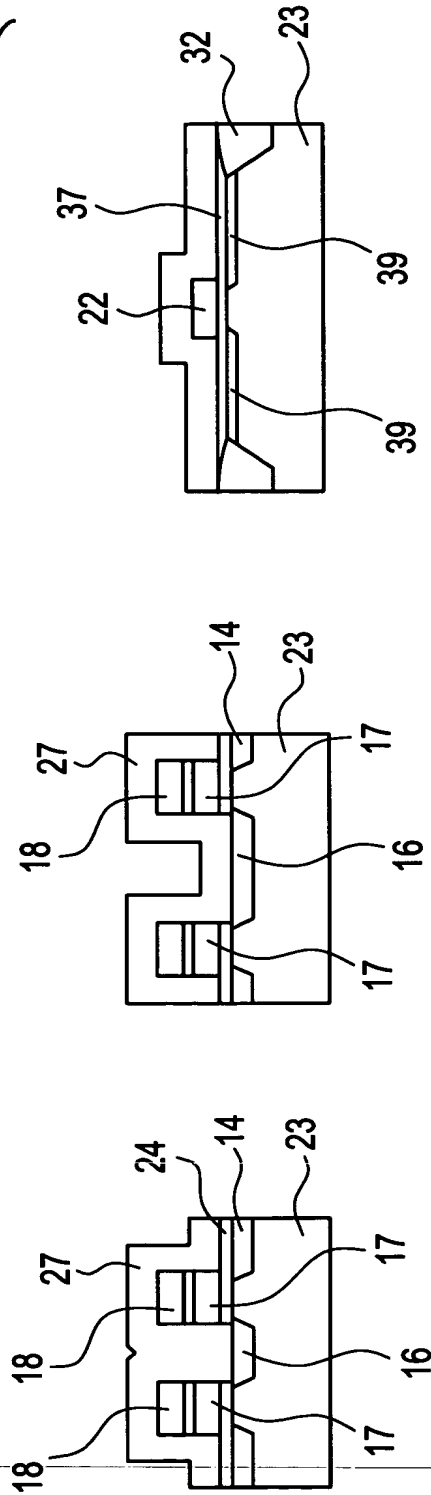


FIG. 10B

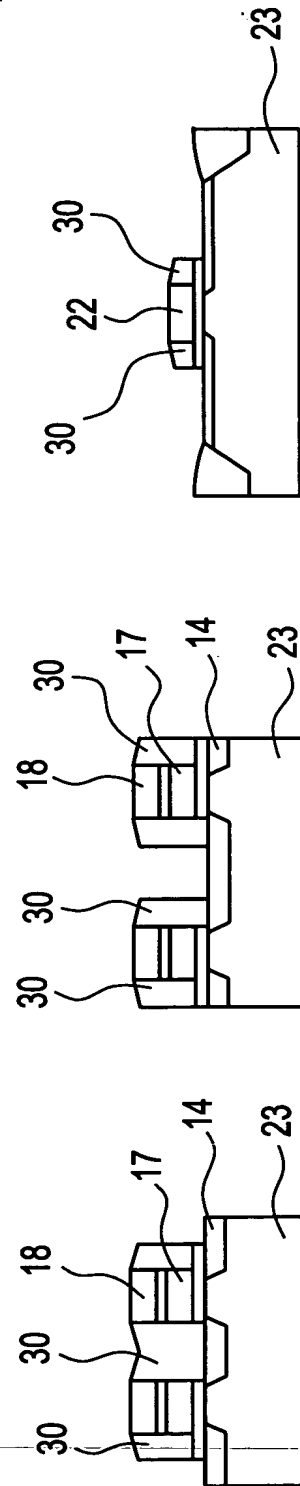


FIG. 10C

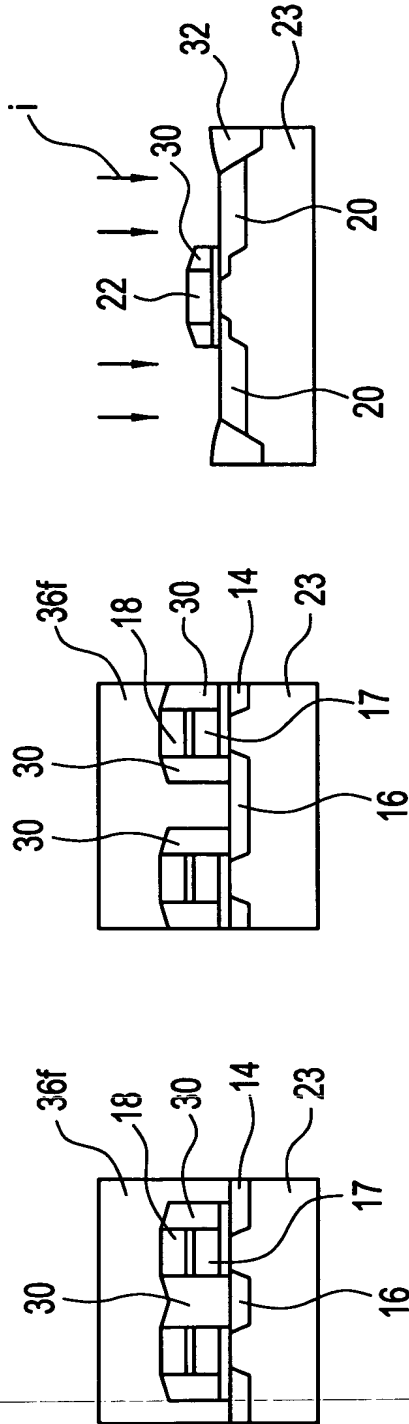
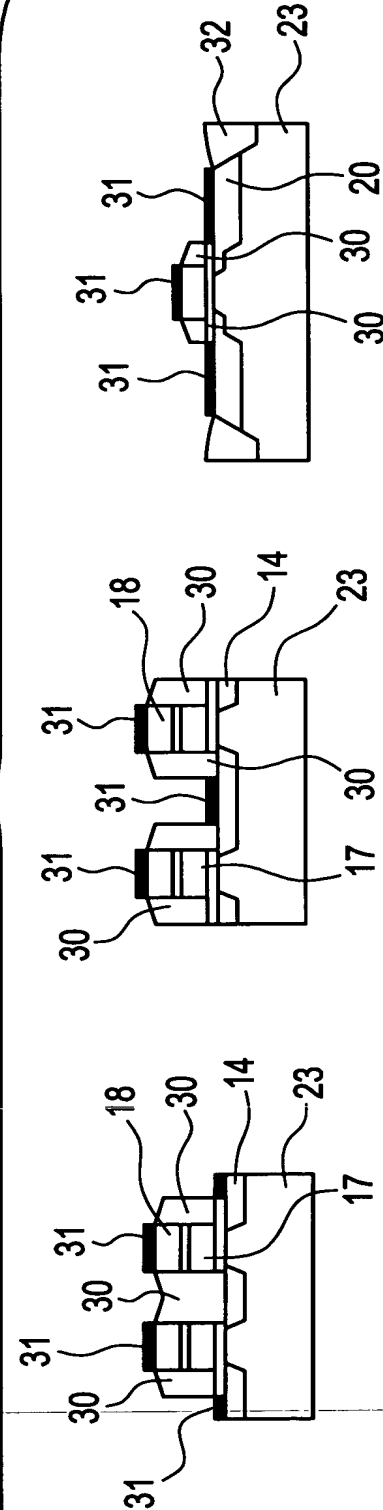


FIG. 10D

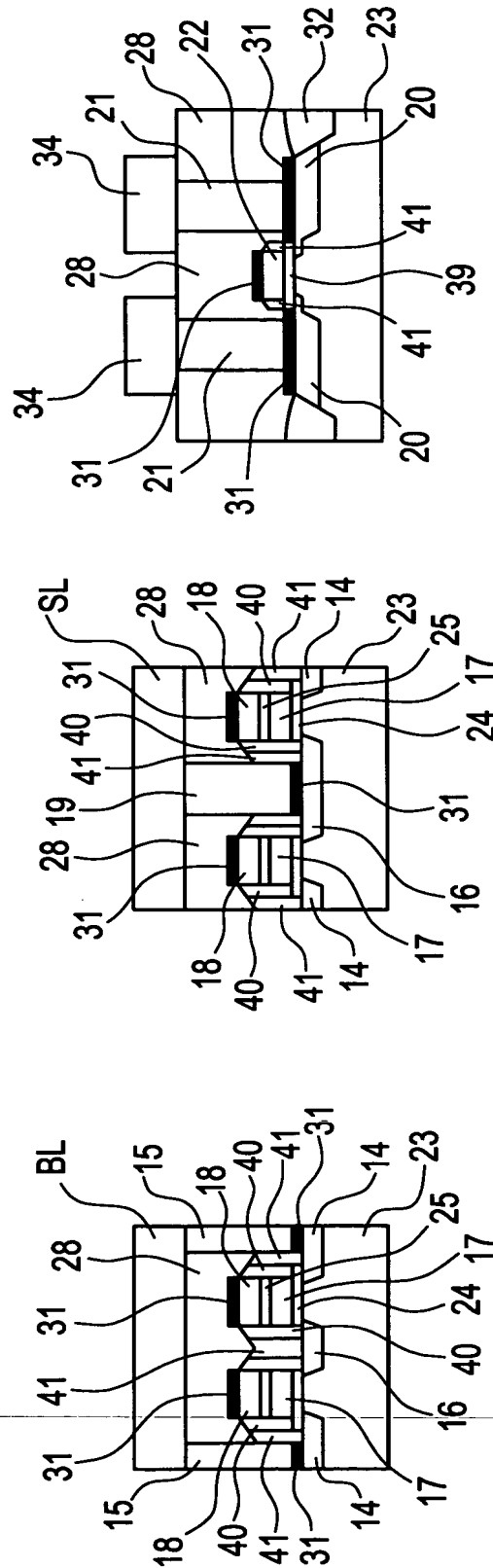


APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

17/20

FIG. 11



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

18/20

FIG. 12A

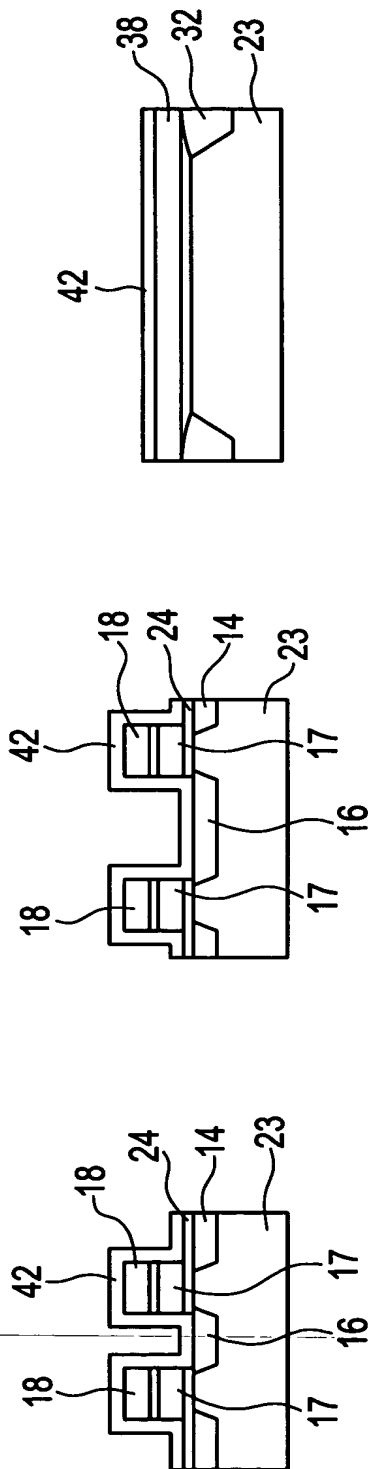
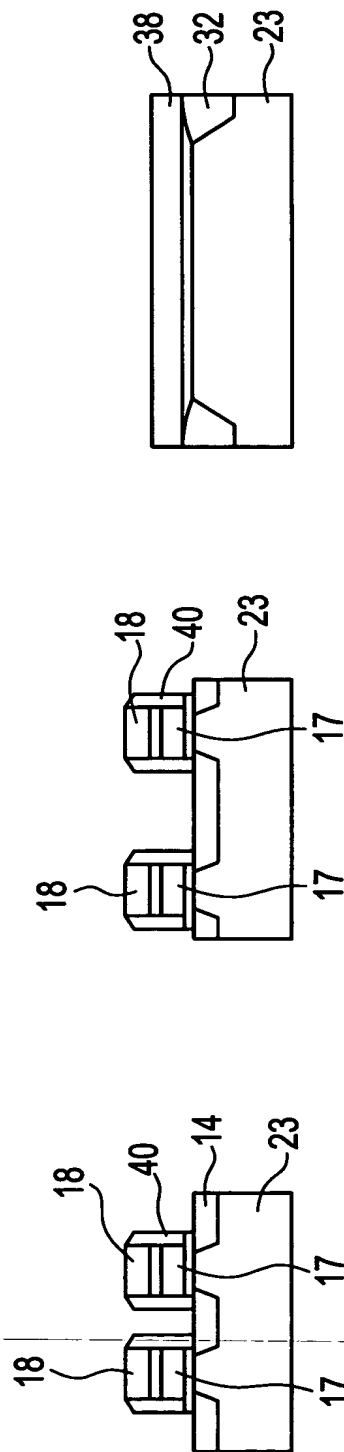


FIG. 12B



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fumihiko HAYASHI
Semiconductor Storage Apparatus and
Manufacturing Method Thereof
Q62964---Filed May 25, 2001

19/20

FIG. 12C

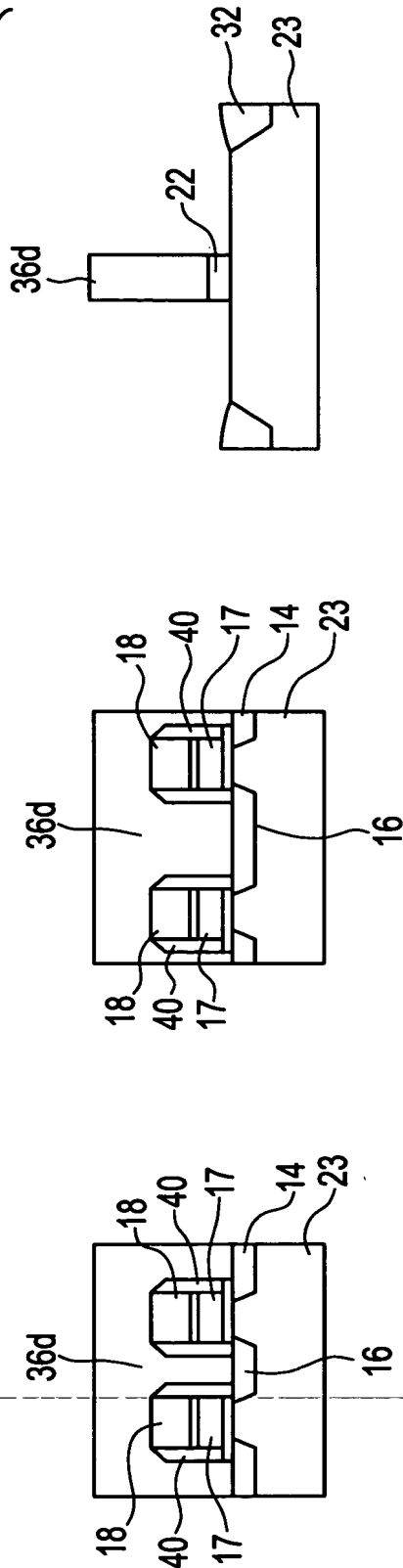


FIG. 12D

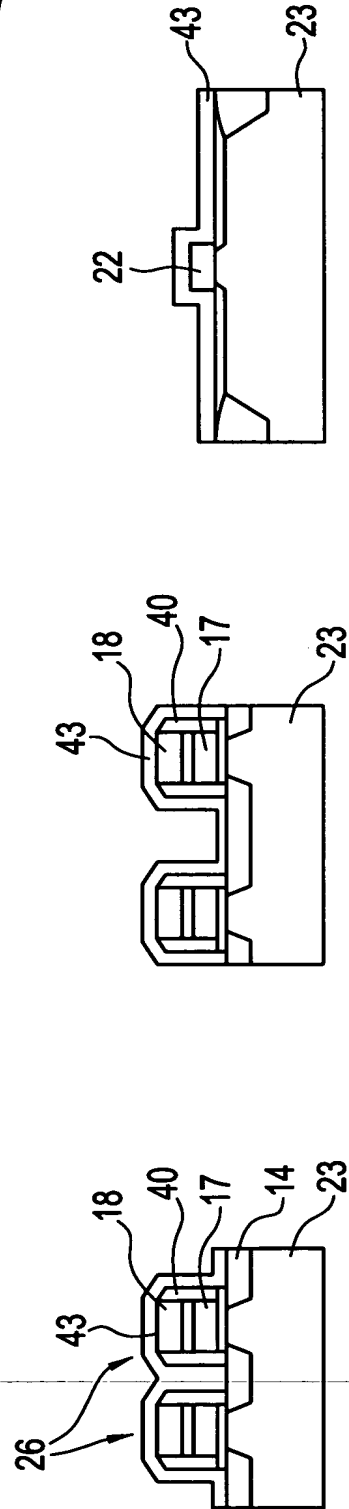


FIG. 12E

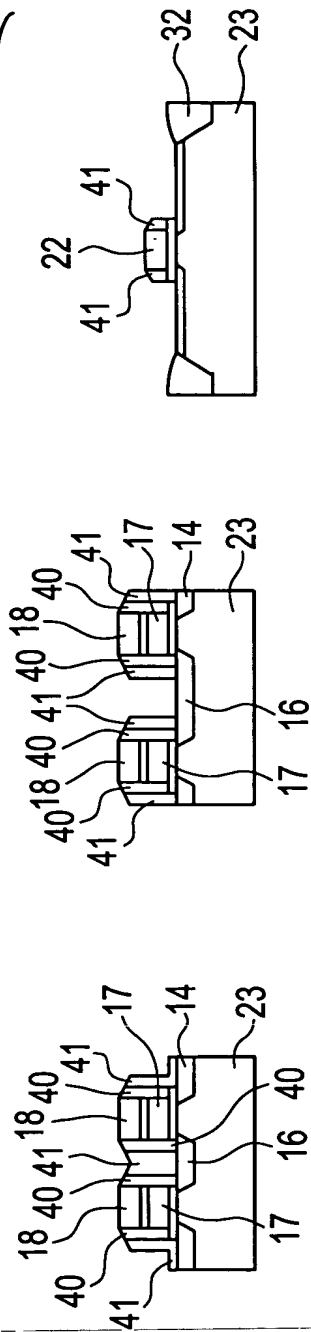


FIG. 12F

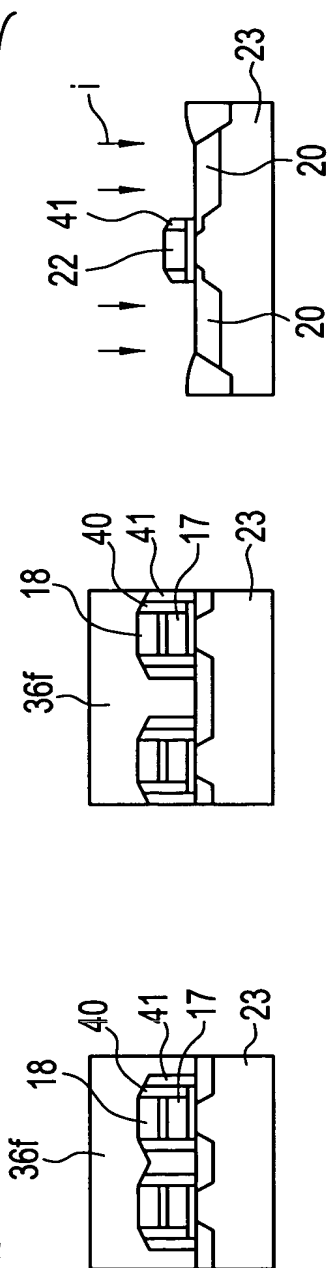


FIG. 12G

